Abstract

Porous silicon nanoparticles is an excellent candidate for medical applications as drug delivery devices, for their excellent biocompatibility, biodegradability, and high surface area. In this paper the simple fabrication process of porous silicon by vapour phase strain etch has been observed. The porous silicon nanoparticle has been made by sacrificial technique. This paper also presents the methods of fabrication of porous silicon nanoparticle and measurement of its particle size by dynamic light scattering. Porosity and thickness of porous silicon has been observed by using gravimetric method. Polydispersity index of the dls sample is 0.22.

References
Nanoporous Silicon Prepared by Vapour Phase Strain Etch and Sacrificial Technique


Index Terms

Computer Science
Circuits And Systems
Keywords
Porous Silicon  Vapour Phase Strain Etch  Sacrificial Technique  Dls  Polydispersity
Index
Biodegradable And Biocompatible Property.